

**ABSTRACT**

**Method, Apparatus and Computer Product for Substrate Processing**

5           A method, apparatus and computer product for processing of substrates in at least a part  
of a substrate processing system is provided. In an embodiment, the method includes obtaining,  
using a processing unit, at least one of a rate of processing and a time of processing of a plurality  
of substrate lots to be introduced into a part of the substrate processing system and determining,  
using the processing unit, an order of introduction of the plurality of substrate lots into the part  
10 of the substrate processing system to at least one of increase the rate of processing and decrease  
the time of processing of the plurality of substrate lots.